

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination CHAMBERS, SCOTT A.	
		Examiner Matthew J Song	Art Unit 1765	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,450,812	09-1995	McKee et al.	117/84
	B	US-5,695,863	12-1997	Bloemen et al.	428/212
	C	US-5,362,711	11-1994	Takada et al.	505/476
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Lu et al. "Improved method of nonintrusive deposition rate monitoring by atomic absorption spectroscopy for physical vapor deposition processes". J. Vac. Sci. Technol. A 13(3), May/June 1995. pp 1797-1801.
	V	Hu et al. "Structural tuning of the magnetic behavior in spinel-structure ferrite thin films" Physical Review B Vol. 62, num. 2, Jul 2000, pp R779-R782.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.